

In re Application of:  
Yuxiang Wang, et al.

Serial No.: 10/799,146

Confirmation No.: 7933

Filed: March 12, 2004

For: Method of Depositing an  
Amorphous Carbon Film for  
Etch Hardmask Application


Group Art Unit: 2813

Examiner: Monica D. Harrison

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, or electronically transmitted to the U.S. Patent and Trademark Office via EFS-Web to the attention of Examiner Monica D. Harrison, on the date shown below.

September 13, 2006  
Date

  
Steven H. VerSteege

Dear Sir:

**RESPONSE TO FINAL OFFICE ACTION DATED JULY 13, 2006**

In response to the Final Office Action dated July 13, 2006, having a shortened statutory period for response set to expire on October 13, 2006, please enter this response and reconsider the claims pending in the application for the reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008244/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 5 of this paper.